



# X-ray irradiation update

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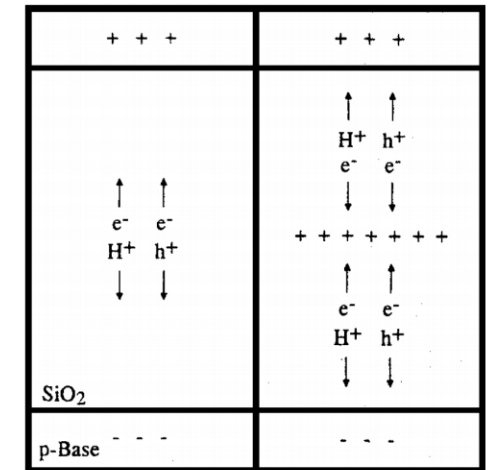
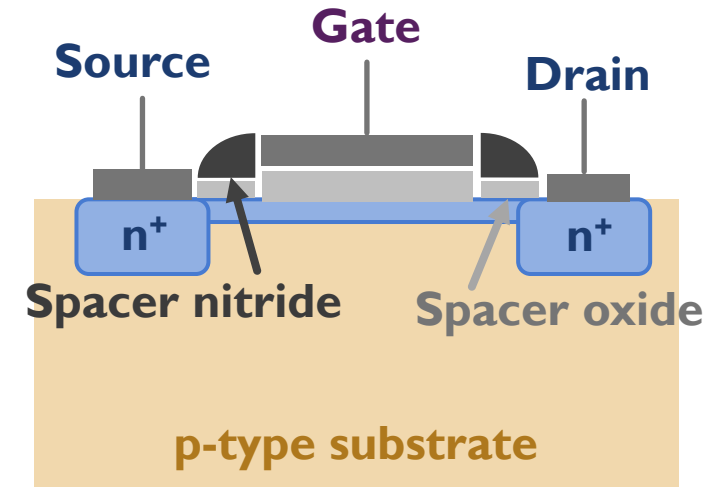
Weekly student instrumentation meeting

25 January 2024



# Radiation damage in transistors

- Radiation damage in transistors mainly dominated by damage in  $\text{SiO}_2$  and at Si- $\text{SiO}_2$  interfaces
  - Radiation damage depends on:
    - Technology (i.e. minimum possible feature size)  $\rightarrow$  65 nm in ITkPix
    - Transistor geometry and layout  $\rightarrow$  W and L of transistor, or W/L, also referred to as transistor strength, smaller transistors suffer more
    - Exact transistor layout
  - Environmental and irradiation parameters:
    - Temperature (**more damage at high temperatures**, maximum operational temperature in HL-LHC expected to be -10 C)
    - Supplied voltage (VDDD voltage in ITkPix chips)
    - **Dose rate:**
      - More damage observed at low dose rates
- $\rightarrow$  Scaling seems to highly depend on the transistor properties, needs to be characterized in detail for ITk



Low Dose Rate

High Dose Rate

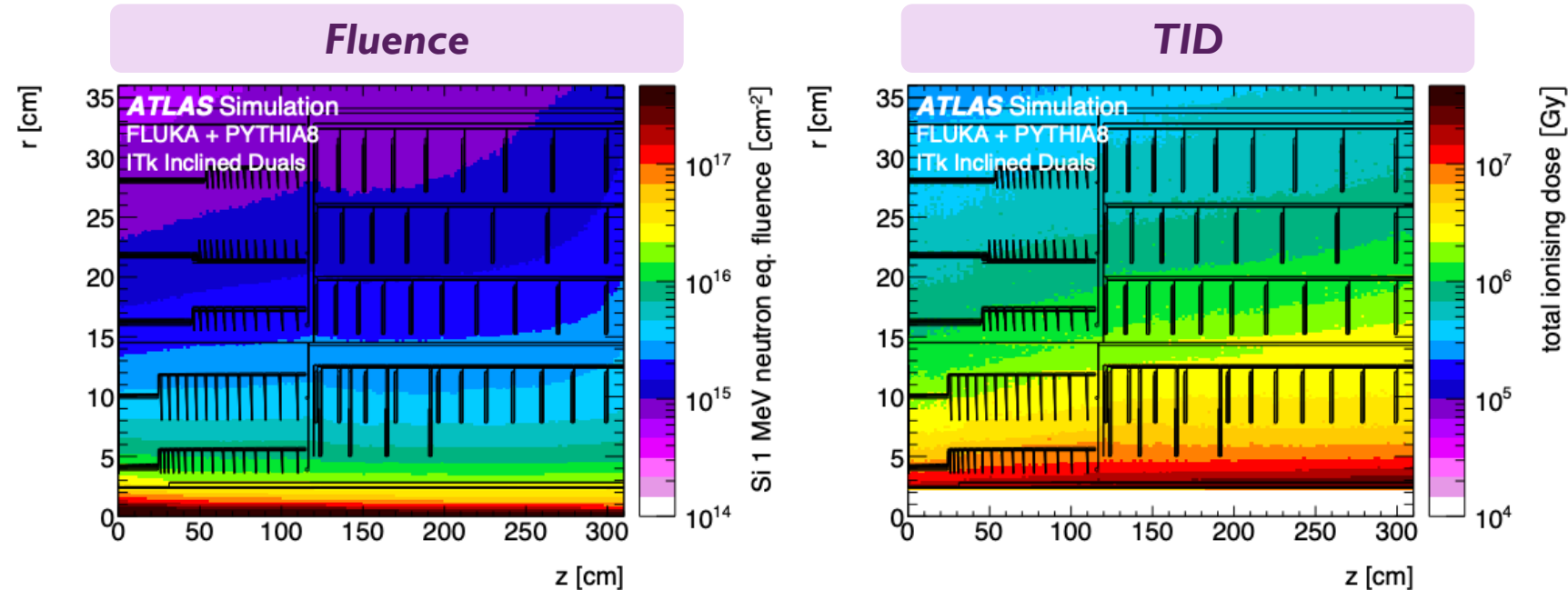
More details in: *F. Faccio et al. 1, 2*

# Expected doses in HL-LHC

- For HL-LHC, expect maximum TID of **1 Grad** and  $1.9 \times 10^{16} \text{ n}_{\text{eq}}/\text{cm}$
- Including 1.5 safety factor
- Innermost ITk layers are planned to be replaced after half of ITk lifetime ( $2000 \text{ fb}^{-1}$ )
- **Dose rate** expected in the innermost ITk layers: **20 krad/h**

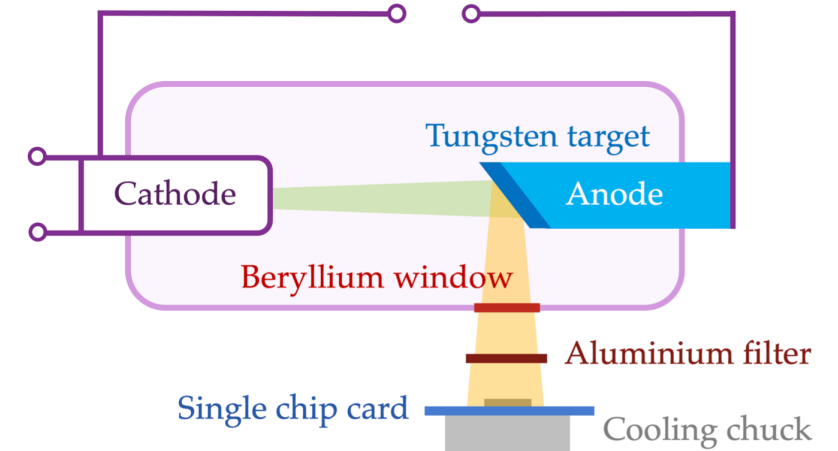
## ATLAS innermost pixel layers

	Fluence	TID
IBL ( $300 \text{ fb}^{-1}$ )	$5 \times 10^{15} \text{ n}_{\text{eq}}/\text{cm}^2$	250 Mrad
HL-LHC ( $2000 \text{ fb}^{-1}$ )	$1.9 \times 10^{16} \text{ n}_{\text{eq}}/\text{cm}^2$	1 Grad



# Irradiation procedures

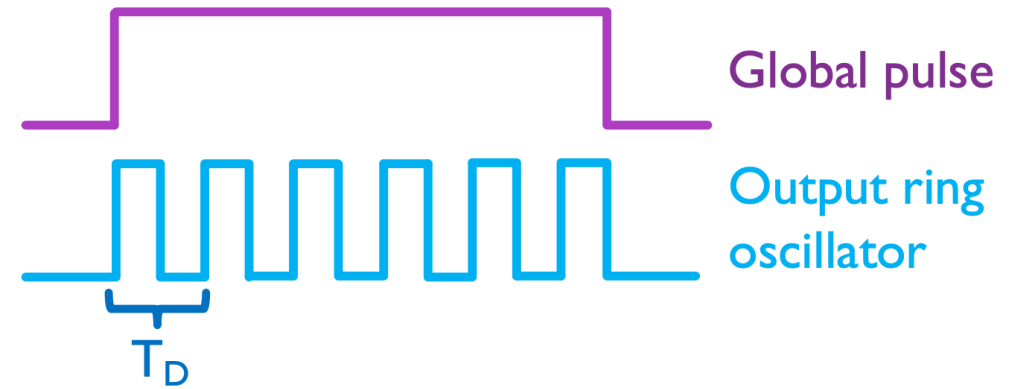
- Performed several irradiation campaigns at varying dose rates for ITkPixV1 and ITkPixV2
- Following common [configuration](#) of X-ray setups for all ITkPixV1 irradiations (40 kV tube voltage, 150  $\mu\text{m}$  Aluminium filter)
- Irradiation procedure:
  - Perform pre-irradiation measurements of ring oscillators
  - During irradiation, read the ring oscillator frequency (at least every 0.1 Mrad) and keep the chip busy by running digital scans
  - Keep the chip cold ( $-10 \pm 1 \text{ C}$ )  $\rightarrow$  Corresponds to maximum expected **operating temperature of chip of  $-7.5 \text{ C}$**  ([Details](#))
  - Monitor the VDDD voltage and temperature
- Additionally, perform long-term low dose rate irradiation of RD53A chip, using Kr-85 source (at the expected HL-LHC dose rate of 20 krad/h)  $\rightarrow$  (**SLow Irradiation of Phase-2 PixEl Readout**)





# Ring oscillators in ITkPixVI

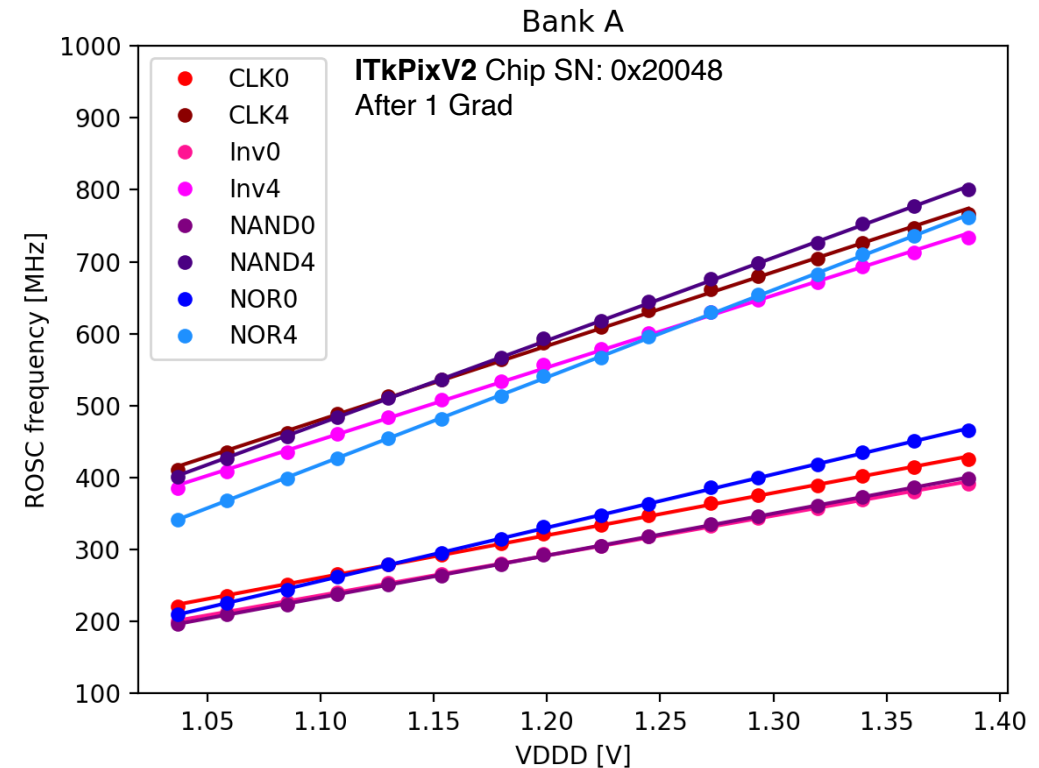
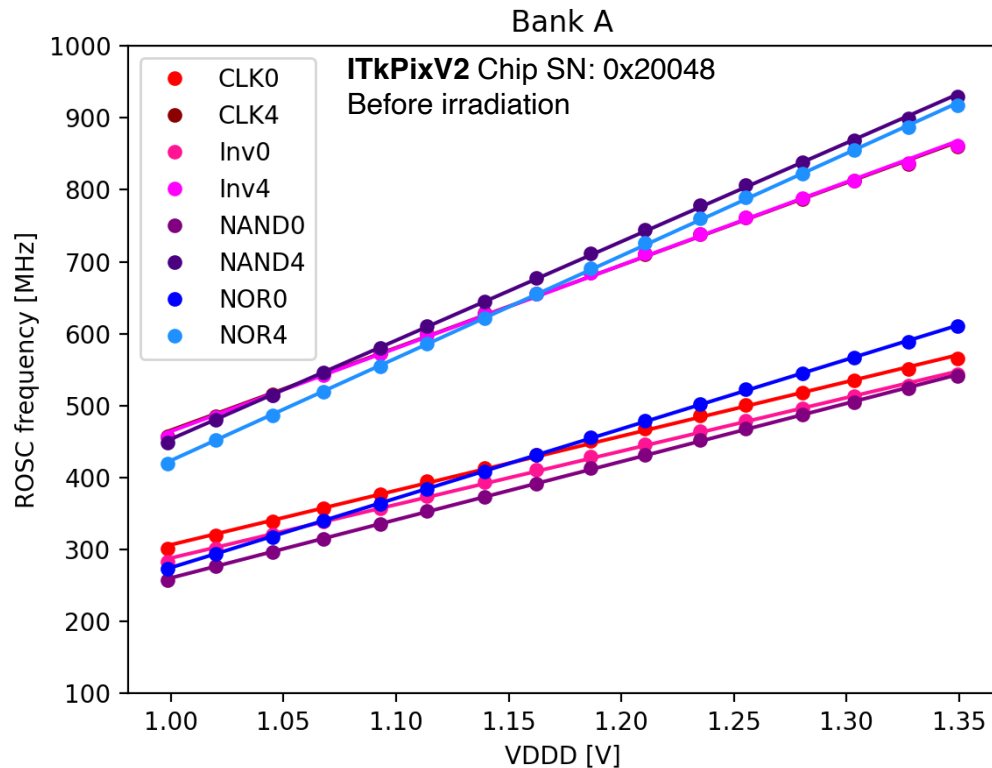
- ITkPixVI/2 chip includes ring oscillator for radiation testing (located at chip bottom)
- 42 ring oscillators made with different logic cells and different transistor sizes (strength 0, 1 and 4)
- ITkPixVI actual digital logic does not use strength 0 gates anymore
- Bank A has exactly the same ring oscillators as RD53A
- Bank B includes 34 additional ring oscillators
- Each oscillator drives a 12-bit counter, enabled for a given period of time
- **Calculate frequency  $f$  or delay  $T_D = 1/(N f)$**
- Delay before irradiation of order 0.1 ns
- During irradiation the gate delay increases
- **Too large (>200%) delay will cause digital logic to fail**



Group	Types	#
A/B	CLK, Inv, NAND, NOR	3 x 8
B FF	Various flip-flop gates	6
B LVT	LVT inverter & 4-input NAND	4
B CAPA	Injection-capacitor loaded 4-input NAND	8

# Ring oscillator vs VDDD

- Before irradiation, characterise ring oscillator frequency as a function of VDDD
  - See the expected linear behaviour with VDDD, and can use the slopes to correct ring oscillator frequencies to account for drifts in VDDD with irradiation
- Repeat the curves after irradiation, as the slopes change with irradiation and interpolate between the two points for the correction

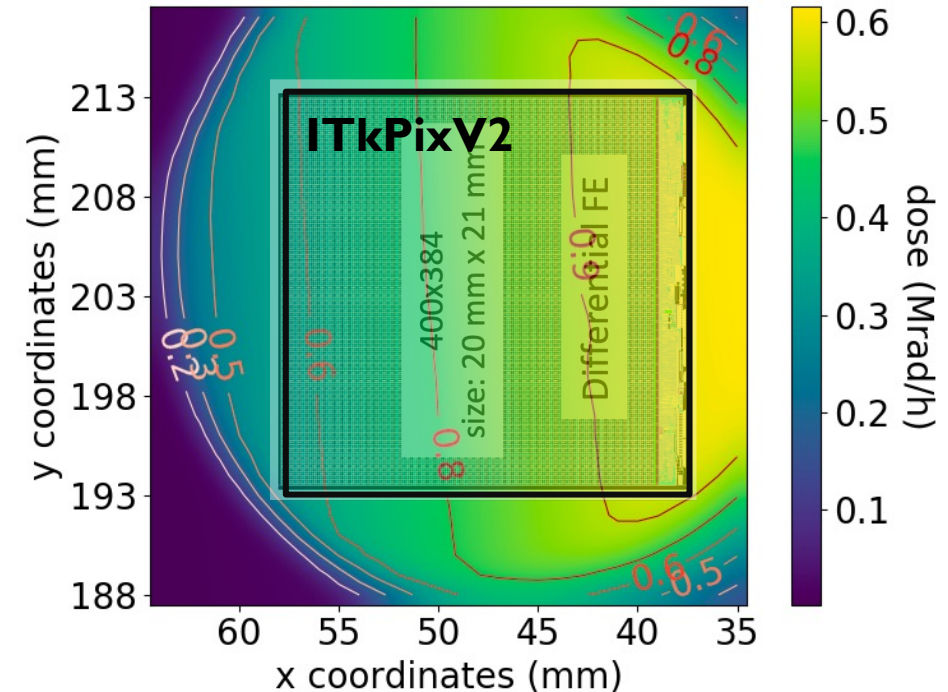


# LBL X-ray setup

- Many X-ray irradiations performed to characterise radiation tolerance for ITkPixV1
- Need to repeat measurements for ITkPixV2 and continue characterisation of the different chip features
- Ran one X-ray irradiation in Oxford last year (at 5 Mrad/h), see [this update](#)
- Also set up X-ray irradiation at LBL → dose rate of 0.5 Mrad/h and non-uniform beamspot
- Irradiation focused on **end of chip** (i.e. chip voltages and ring oscillators)
- Monitor everything available via the VMUX, and measure ring oscillators



z = #3 cm at 50 mA



# Environmental monitoring

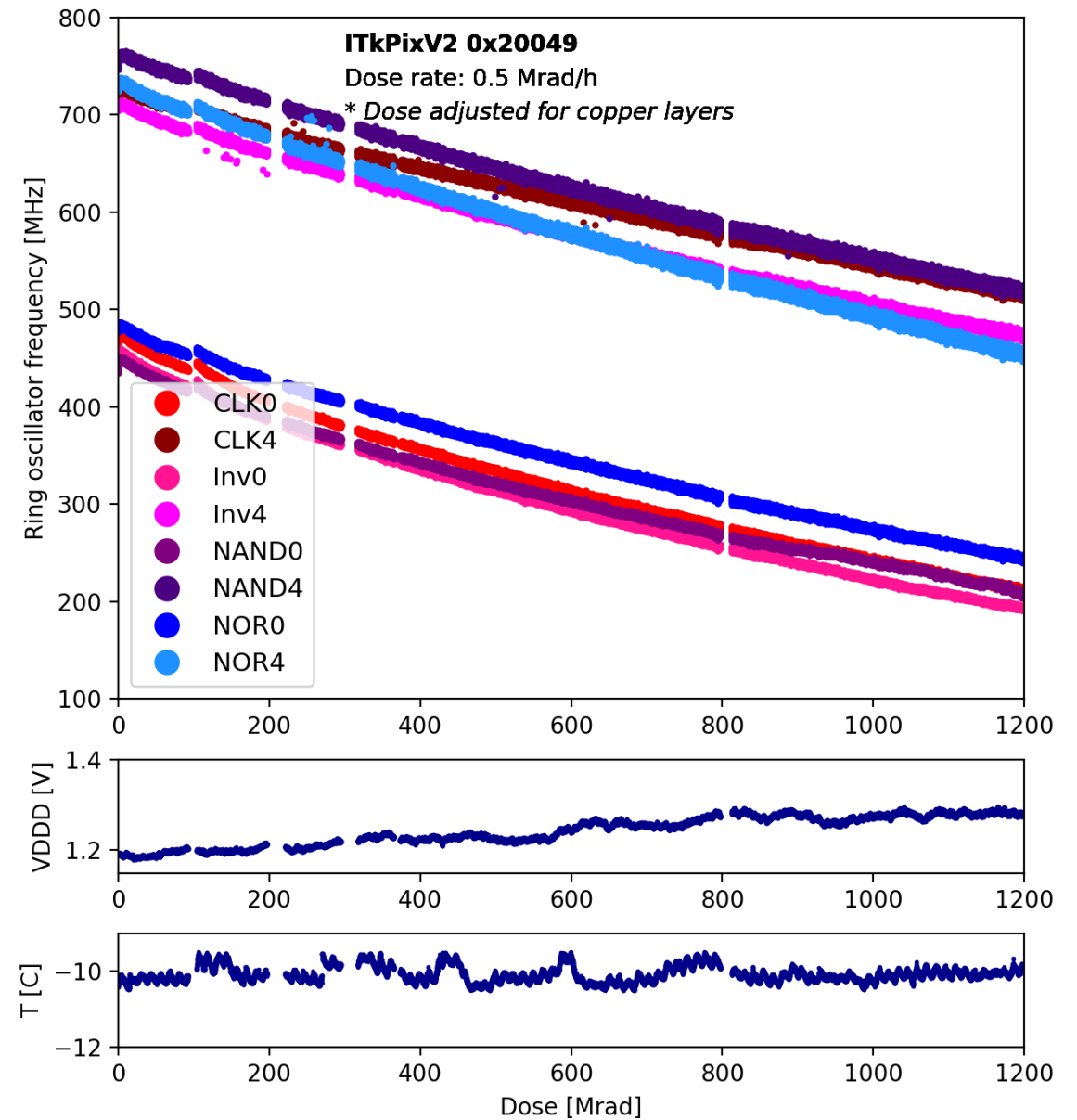
- Irradiation ran from September until the Christmas break
- Set up Grafana to monitor irradiation status
- Generally irradiation ran smoothly
  - Had to power down X-ray machine once due to power outage
    - Left the chip warm and unpowered
  - Irradiation script crashed a few times
    - Need to make more reliable and set up alerting for next time
- Reached total dose of 1.2 Grad





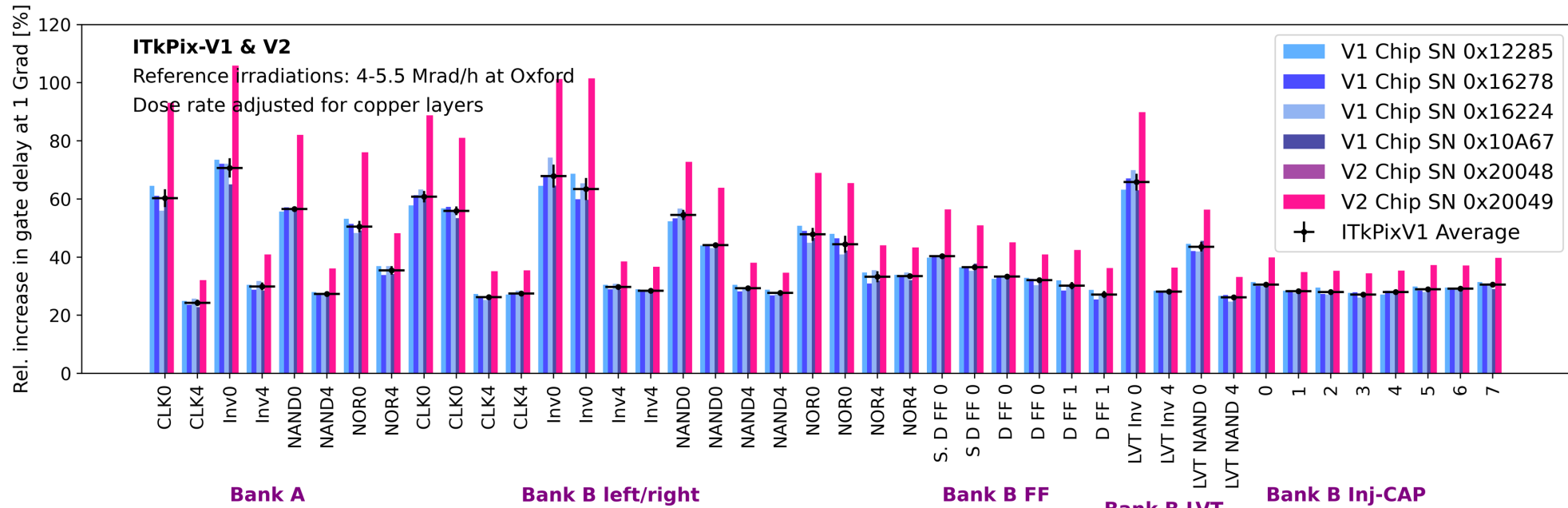
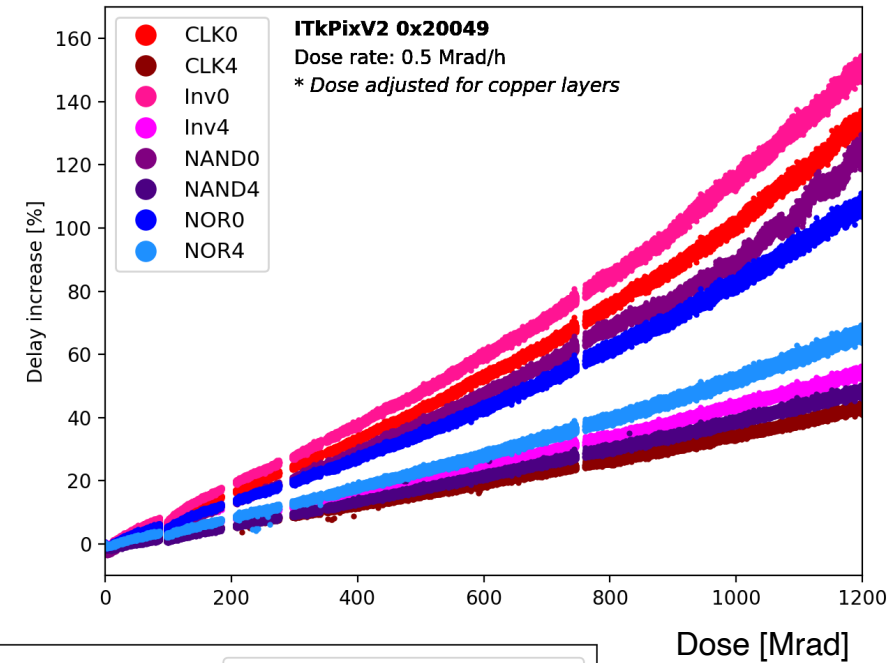
# Ring oscillators

- Ring oscillator frequency with irradiation
  - Corrected for drift of VDDD with irradiation
  - Stopped irradiation at ~100 Mrad due to power outage
- Can see some annealing happened but with when restarting irradiation frequency continues with the same trend



# Ring oscillators

- Can also compute gate delay increase with irradiation (requirement < 200%)
- Steady increase, start to see some non-linearity for the strength 0 gates
- Note: Strength 0 gates not used in digital logic of the chip
- Can compare to irradiations in Oxford at 5 Mrad/h → clearly larger gate delay increase in this irradiation at 0.5 Mrad/h



Dose [Mrad]

Bank A

Bank B left/right

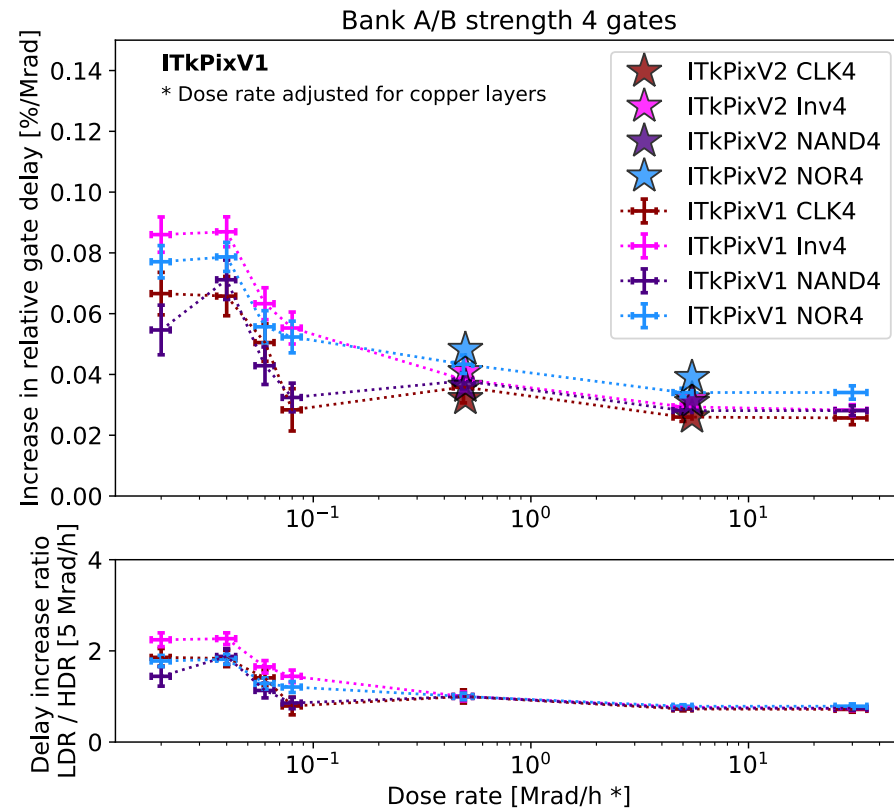
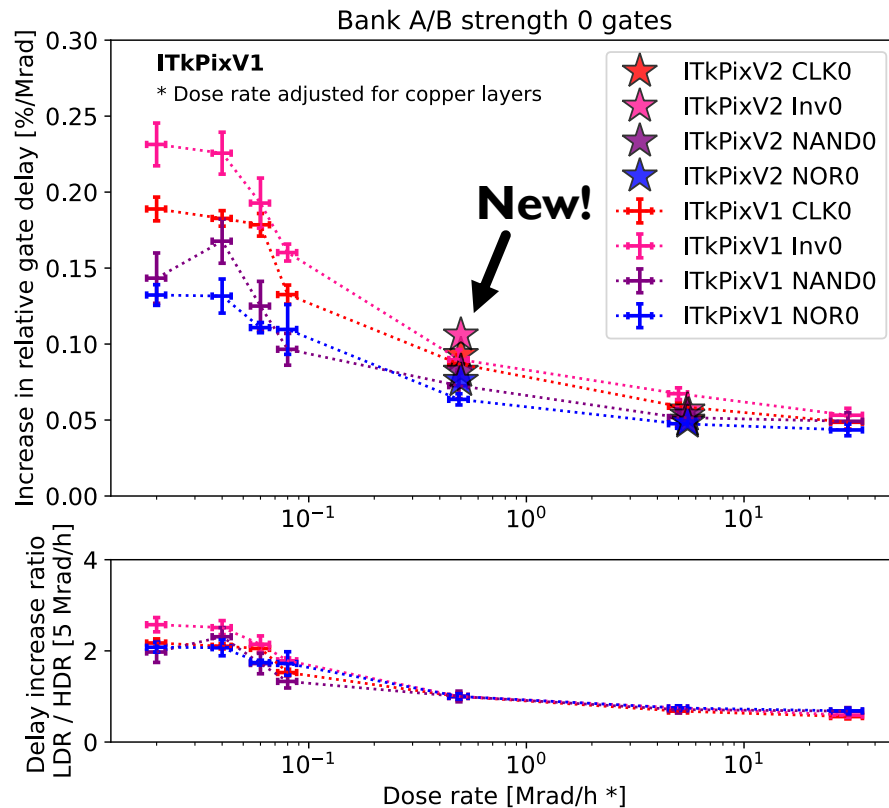
Bank B FF

Bank B LVT

Bank B Inj-CAP

# Low dose rate effects

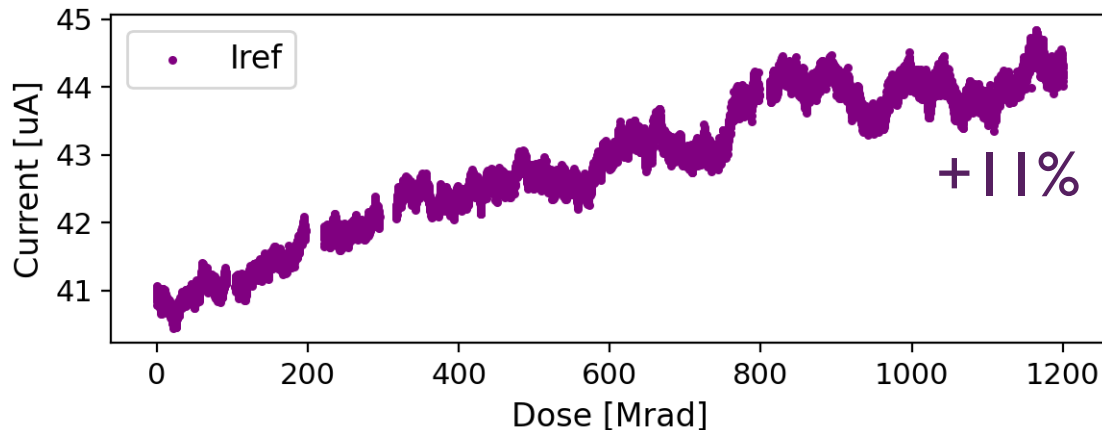
- Well-known dose rate dependence of radiation damage in 65 nm transistors
- Have been collecting data over the past few years using ITkPixV1 → Observe a factor ~2 more damage at the HL-LHC expected dose rates (20 krad/h)
- ITkPixV2 data matches well with existing results



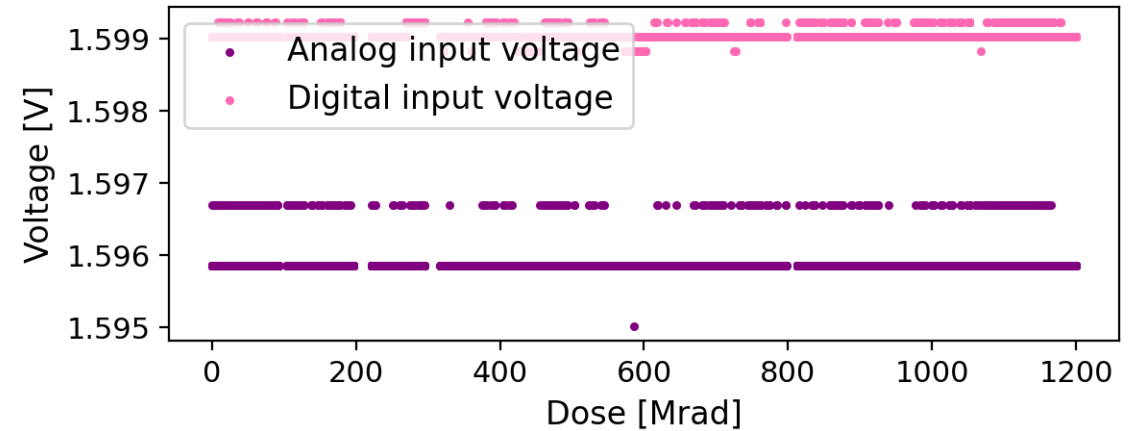
# Chip currents

- Main focus of irradiation were chip voltages and currents
  - Chip powered in LDO mode → constant input voltage
  - Main chip reference current ( $I_{ref}$ ) drifts with irradiation → expected and consistent with ITkPixVI results
  - Analog currents seems to increase significantly with irradiation
- surprising, could be non-uniform irradiation, but if real need to think about implications for ASIC powering envelope

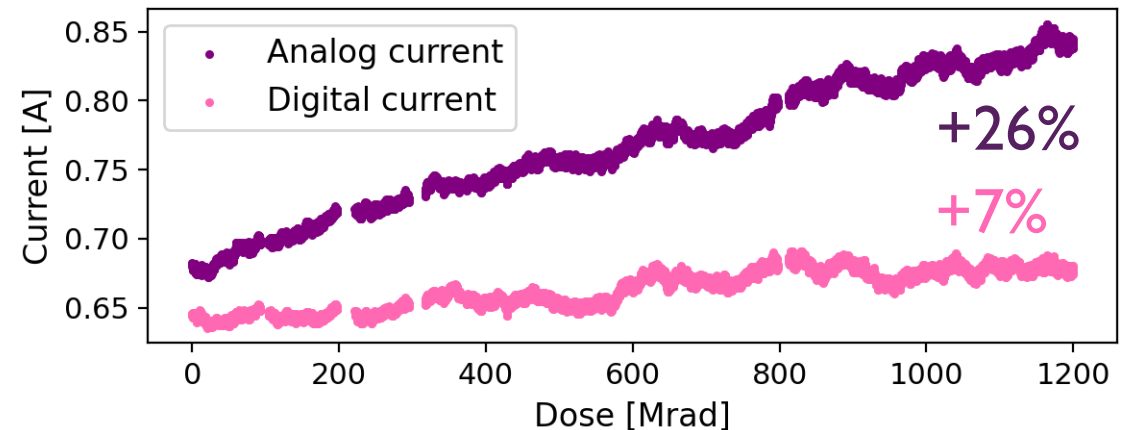
### Main chip reference current ( $I_{ref}$ )



### Power supply voltage



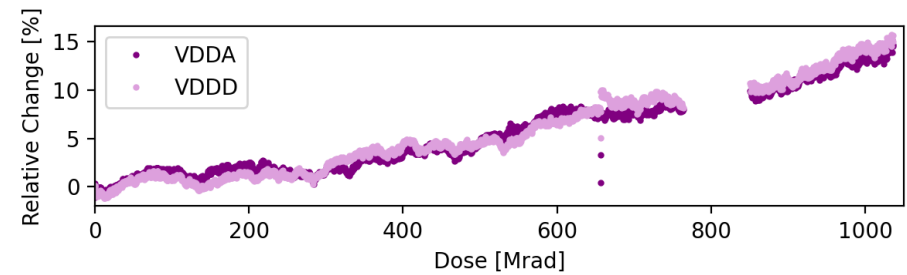
### Power supply currents



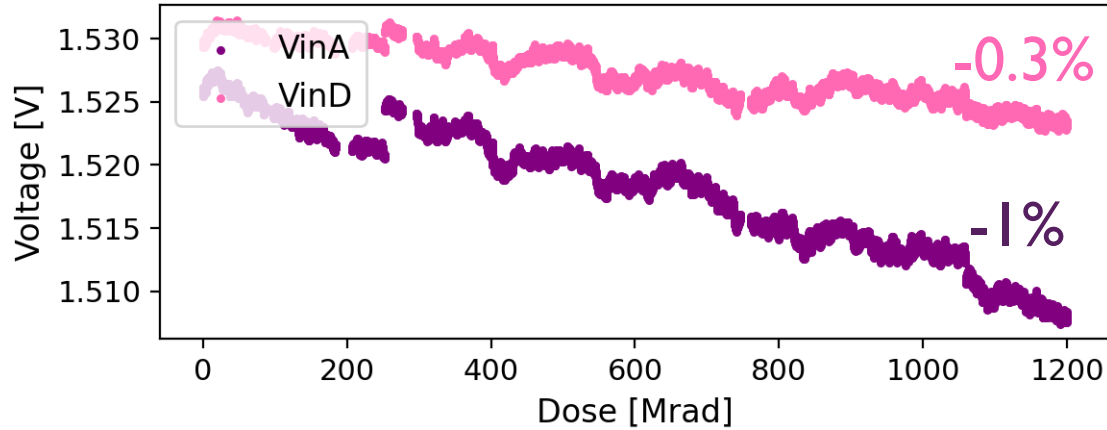


# Voltages

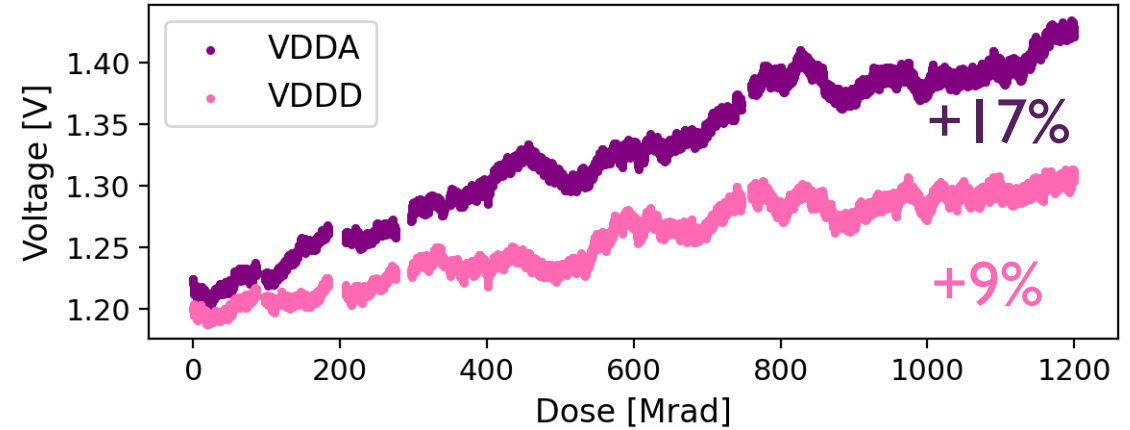
## VDDA/D @ Oxford 5 Mrad/h



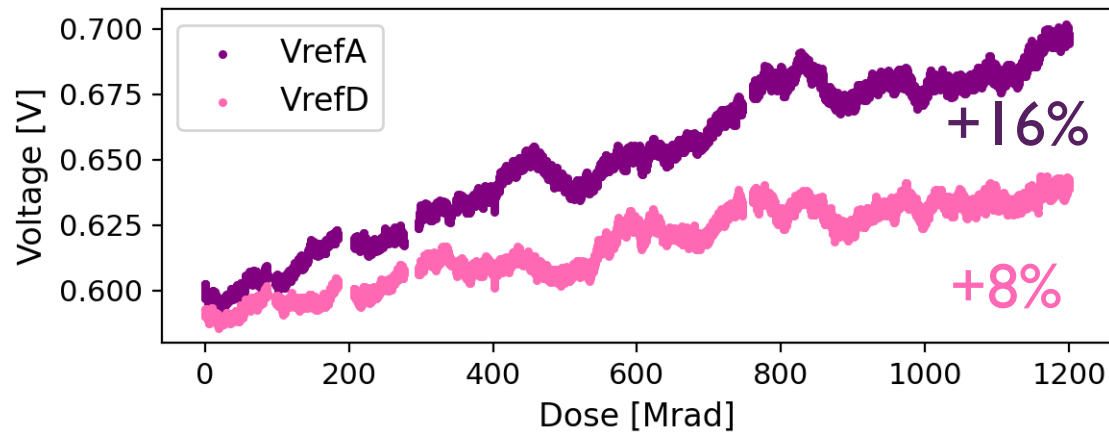
## Chip input voltages



## VDDA/D



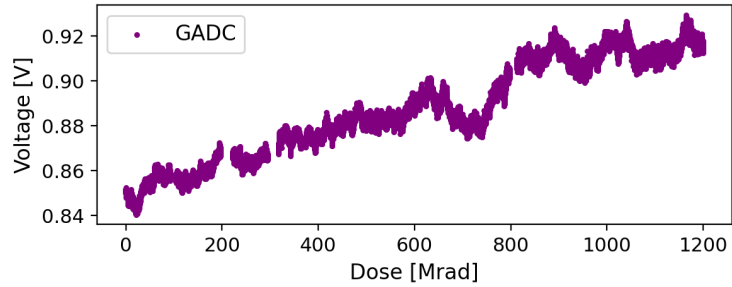
## VrefA/D



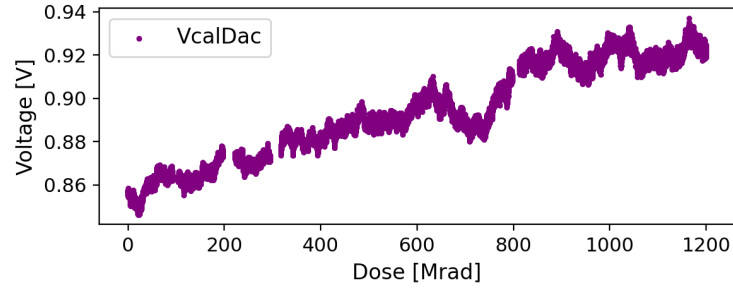
- Input voltage measured on the chip decreases slightly during irradiation
- Vref and VDD increase with irradiation (as they derive from Iref)
- VDDA increases more than VDDD
- surprising, as a fix to metallisation layers was included in ITkPixV2 to make drift more uniform
- Increase was also more similar ITkPixV2 irradiation in Oxford
- Non-uniform irradiation or dose rate effect?

# More voltages...

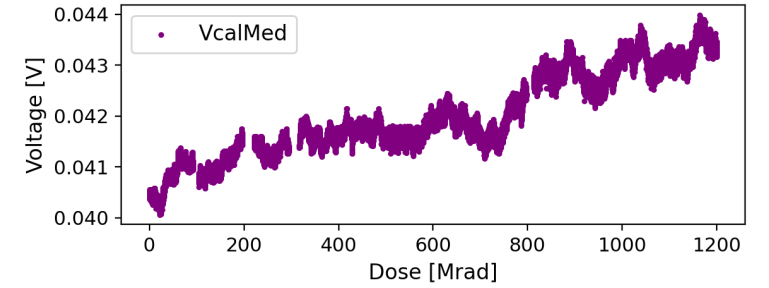
### Vref\_ADC



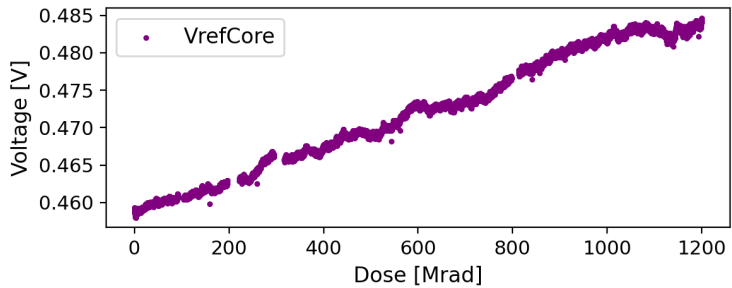
### VCAL\_DAC



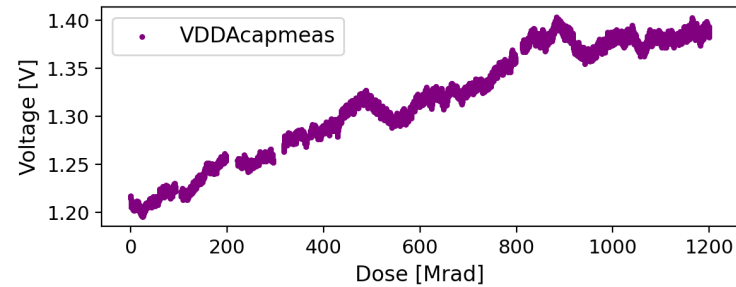
### VCAL\_MED



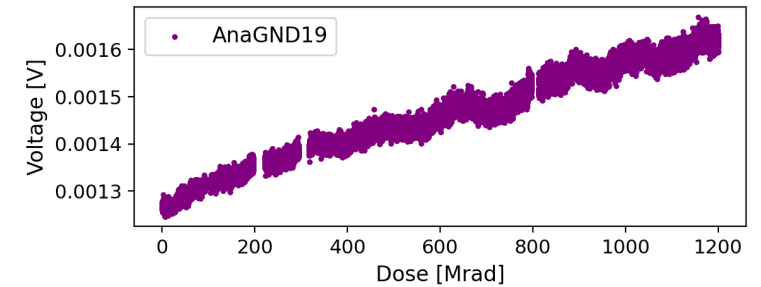
### Vref\_Core



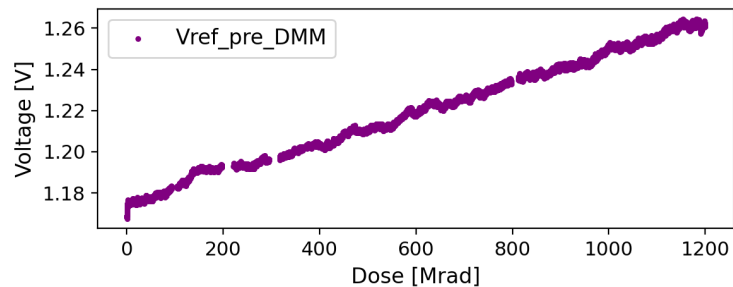
### VDDA capmeasure



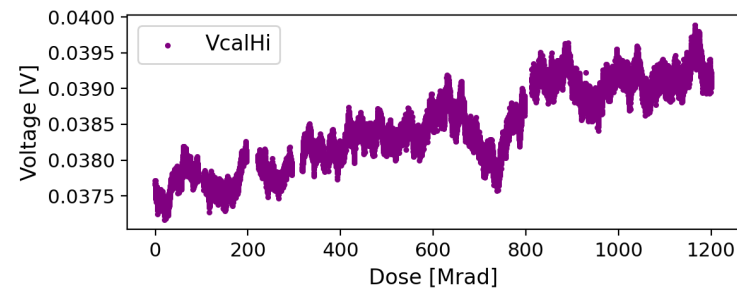
### Analog ground



### Vref\_Pre

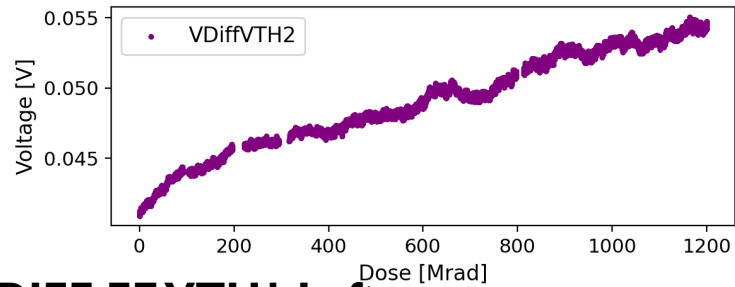


### VCAL\_HI

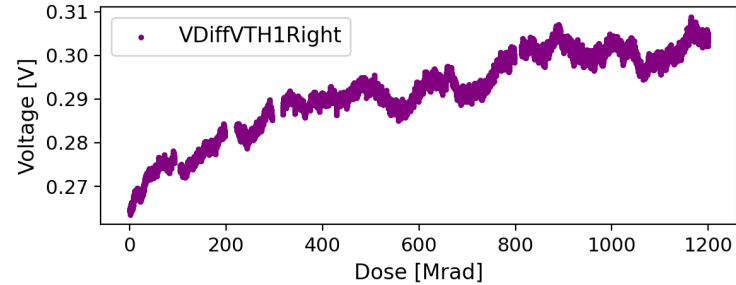


# Even more voltages...

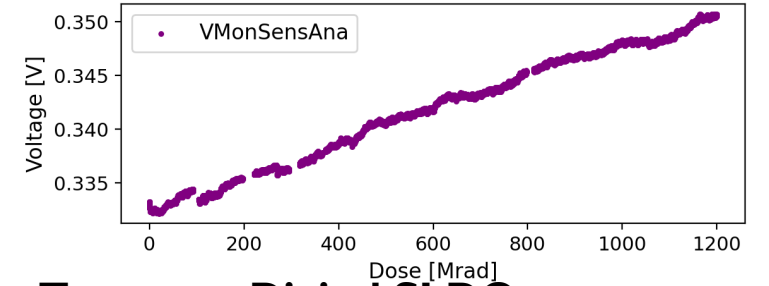
### DIFF FEVTH2



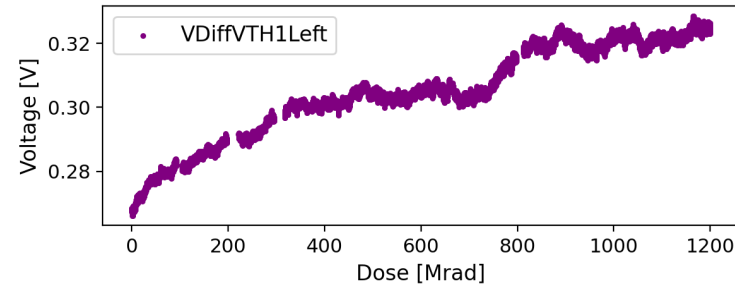
### DIFF FEVTH1 Right



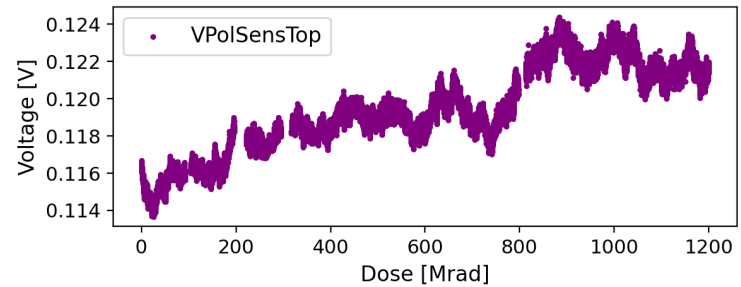
### Tempsens Analog SLDO



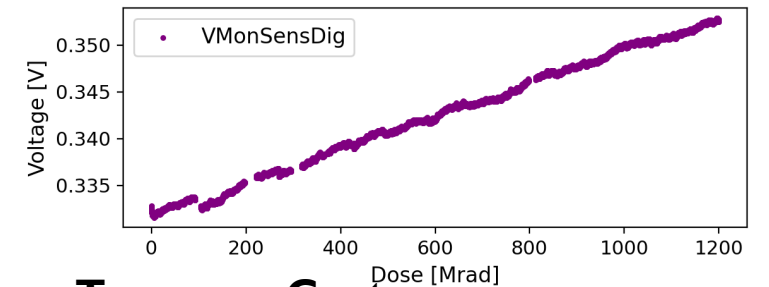
### DIFF FEVTH1 Left



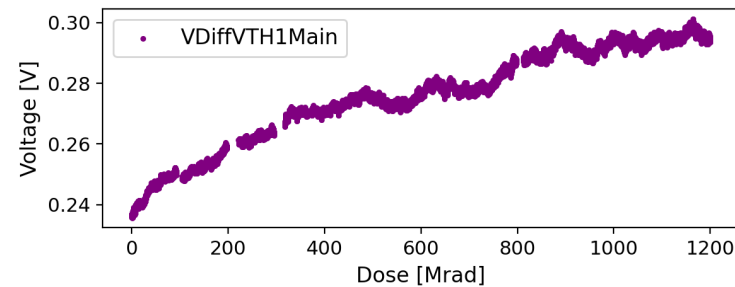
### Poly Tempsens top



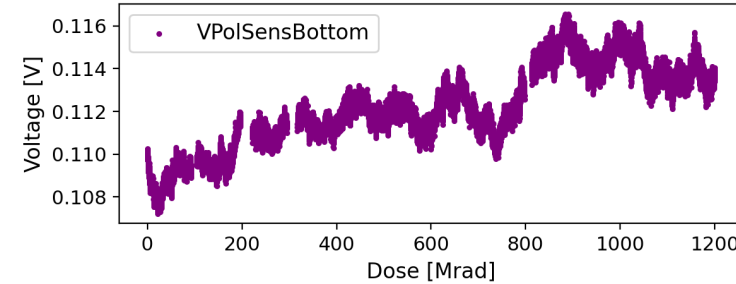
### Tempsens Digital SLDO



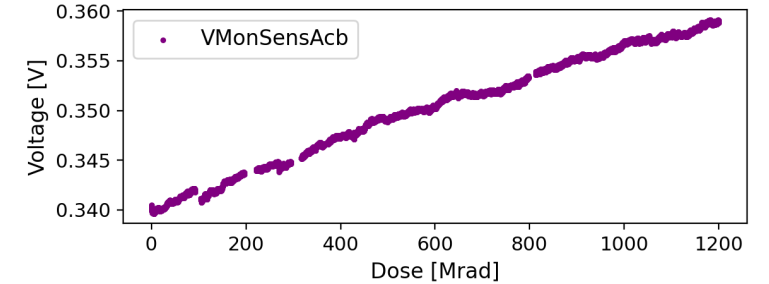
### DIFF FEVTH1 Main



### Poly Tempsens bottom

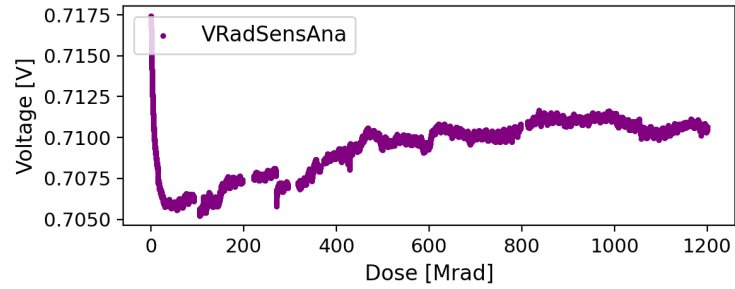


### Tempsens Center

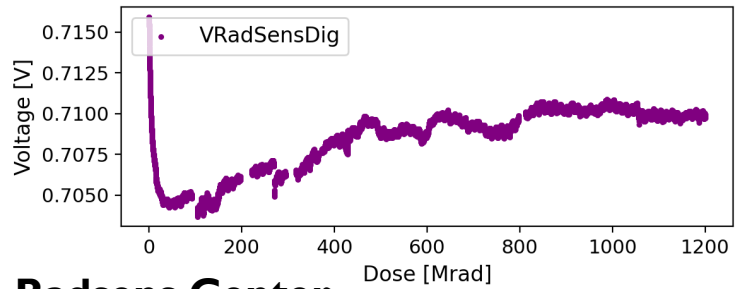


# Radiation sensors

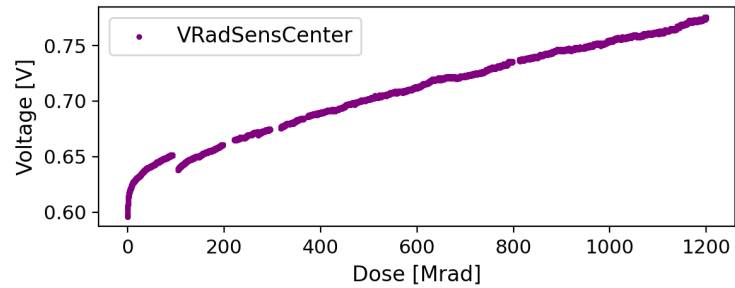
## Radsens Analog SLDO



## Radsens Digital SLDO



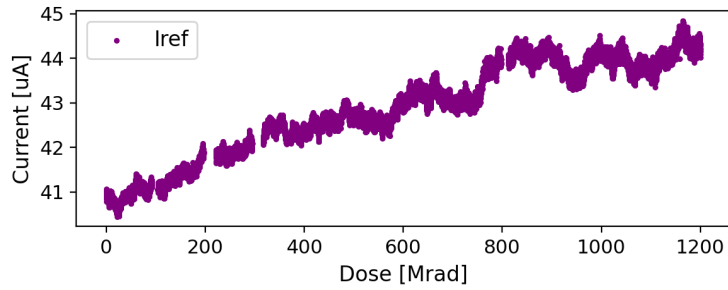
## Radsens Center



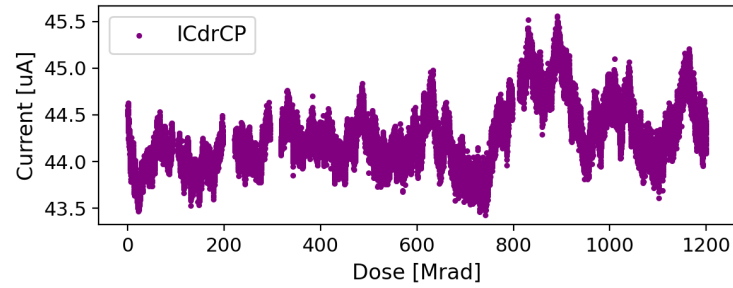


# More currents...

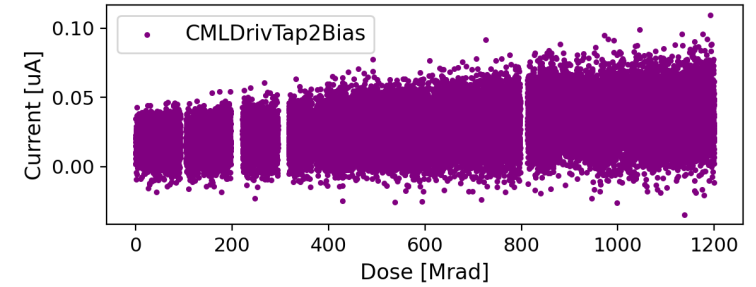
### Iref



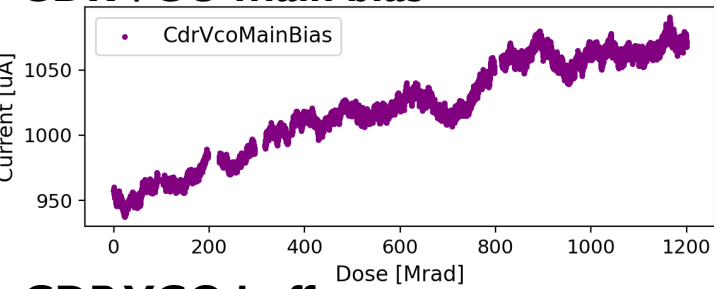
### CDR CP current



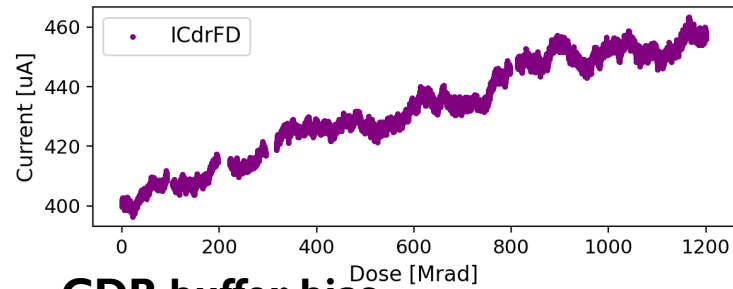
### CML driver tap 2 bias



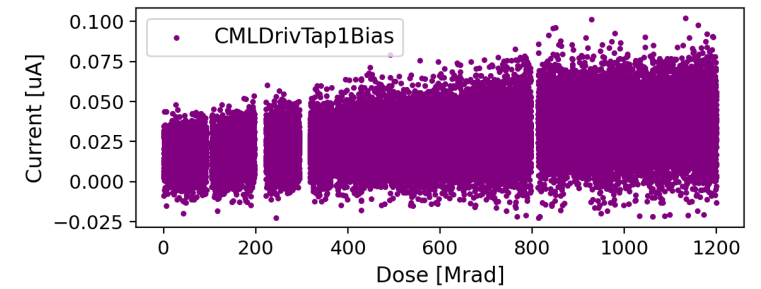
### CDR VCO main bias



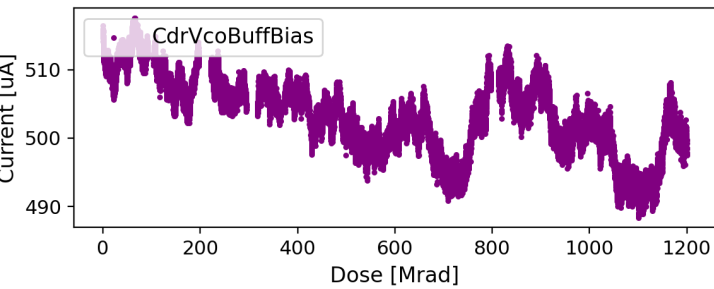
### CDR FD current



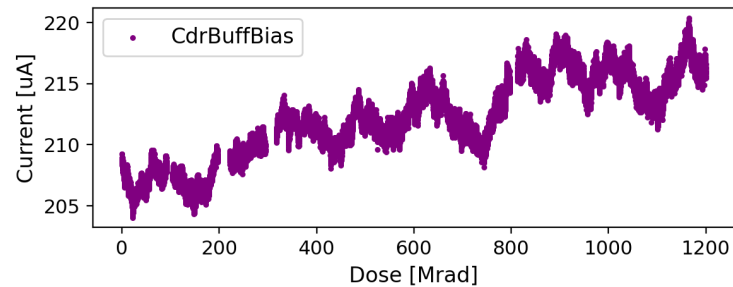
### CML driver tap 1 bias



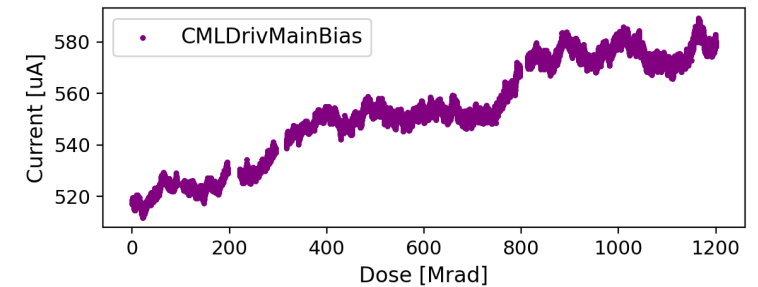
### CDR VCO buffer



### CDR buffer bias

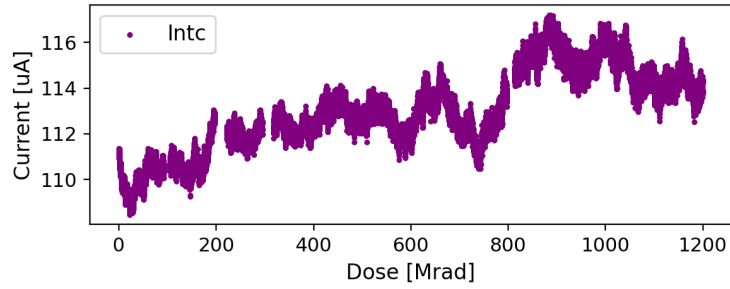


### CML driver tap main bias

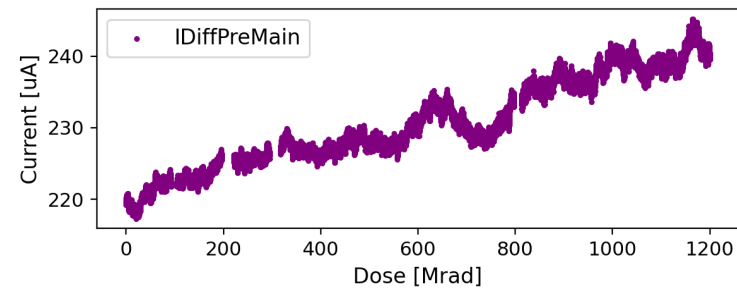


# More currents...

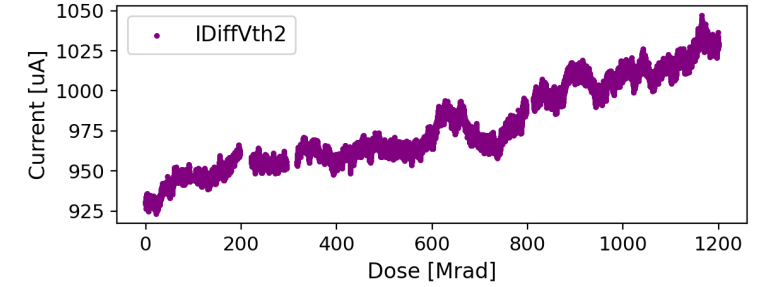
## NTC pad current



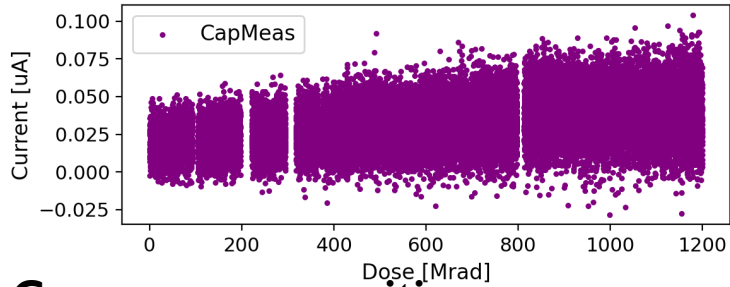
## Preamp Main



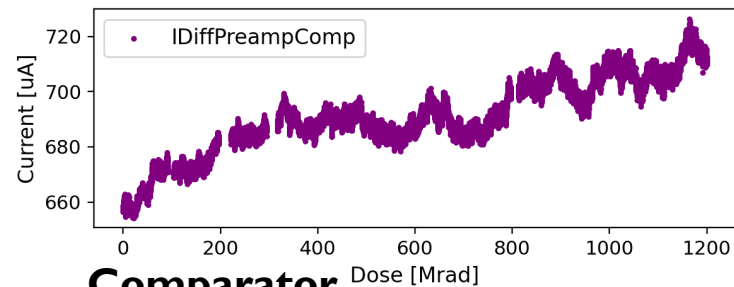
## Vth2



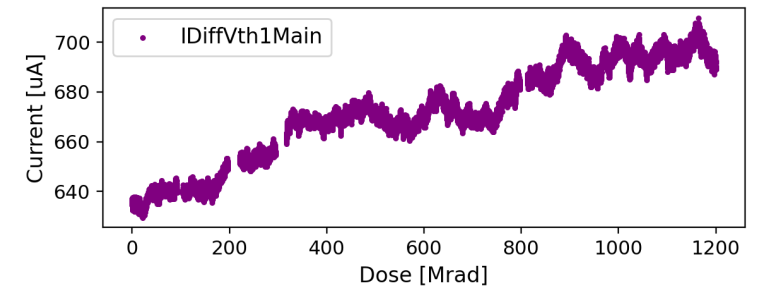
## Capmeasure circuit



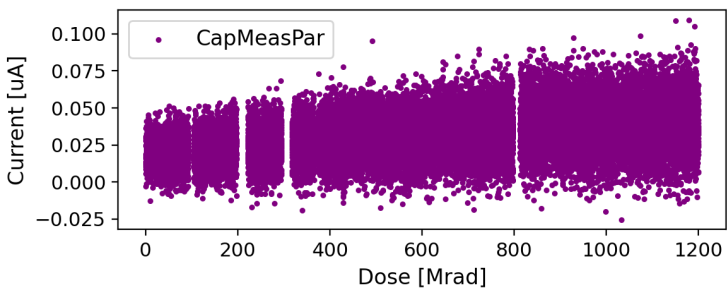
## PreComp



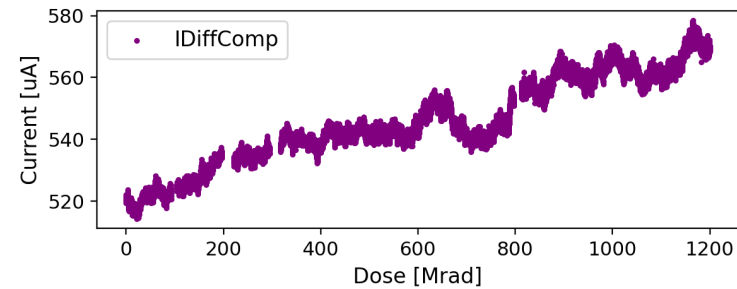
## Vth1 main



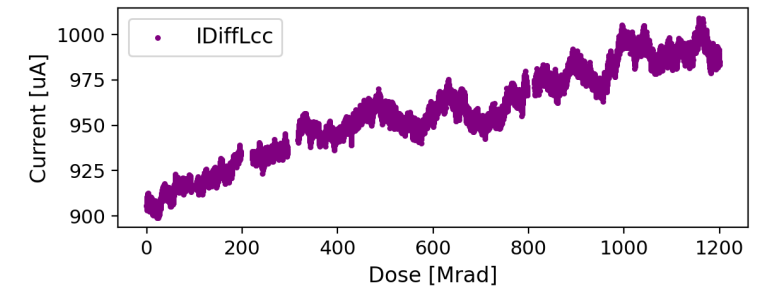
## Capmeasure parasitic



## Comparator

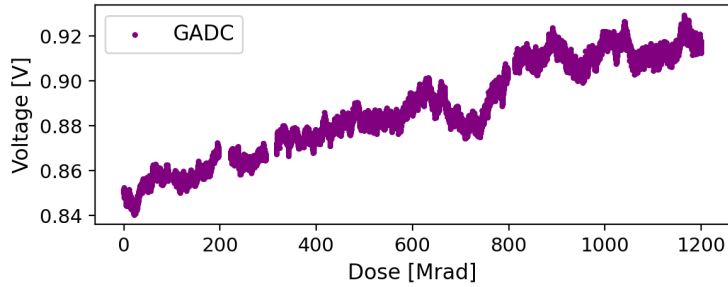


## LCC

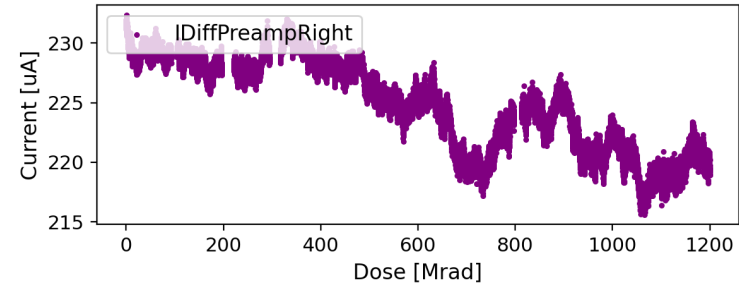


# More currents...

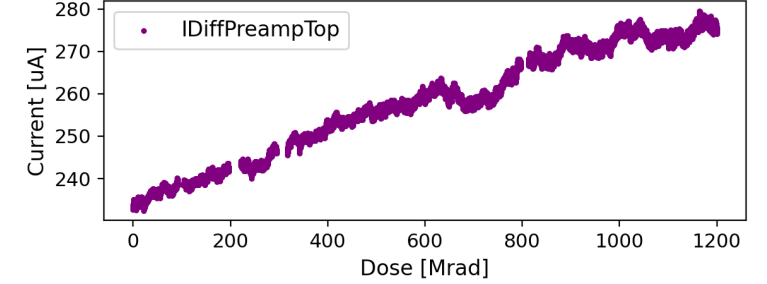
## Feedback



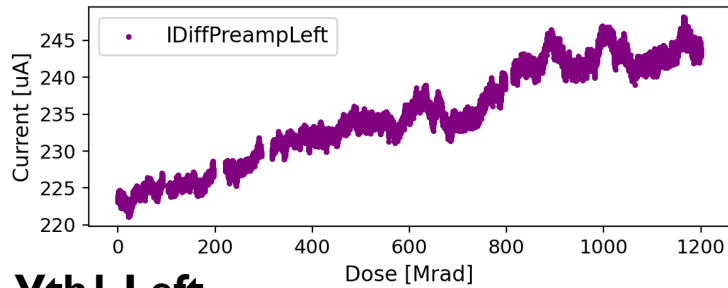
## Preamp right



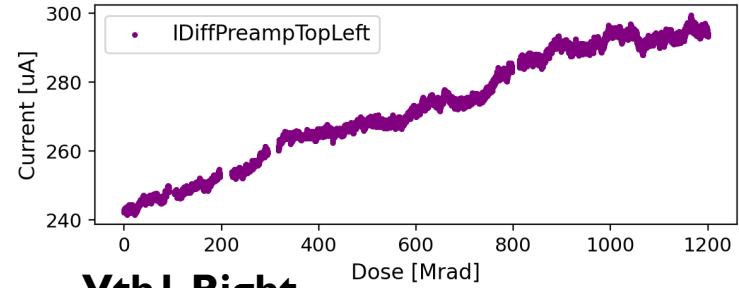
## Preamp Top



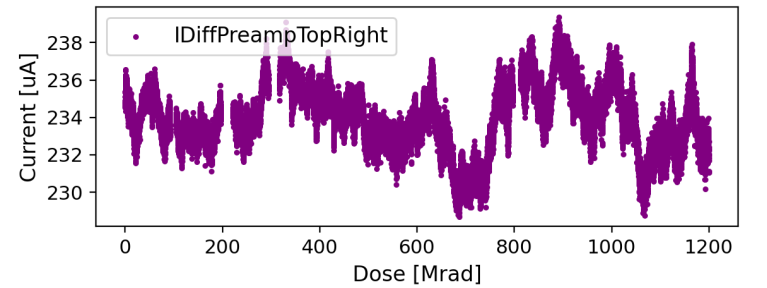
## Preamp Left



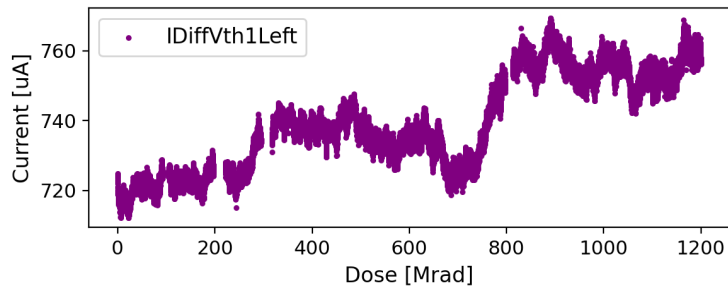
## Preamp top left



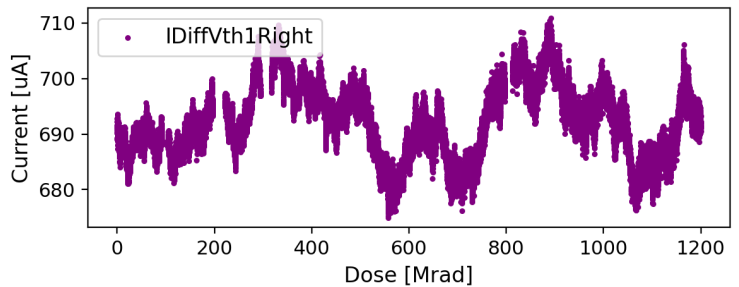
## Preamp top right



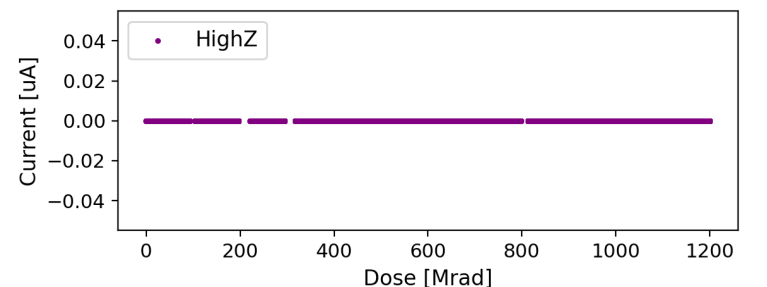
## VthI Left



## VthI Right

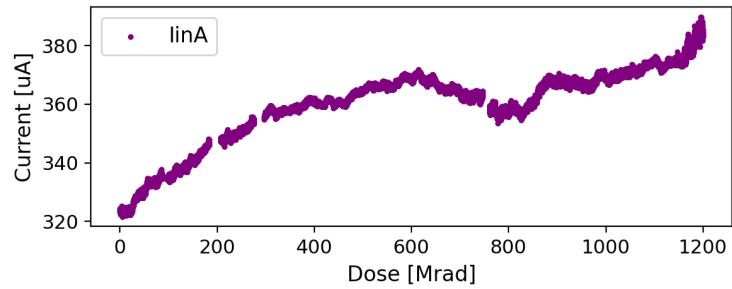


## High Z

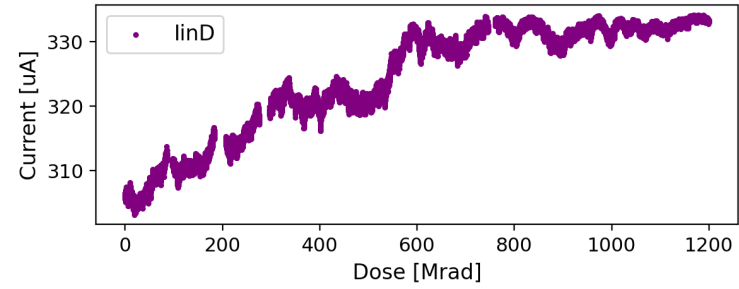


# More currents...

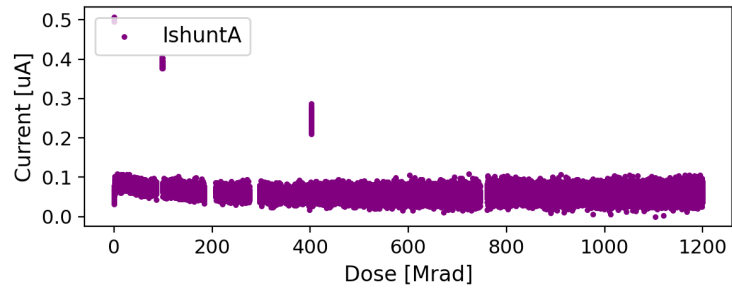
## Analog input current



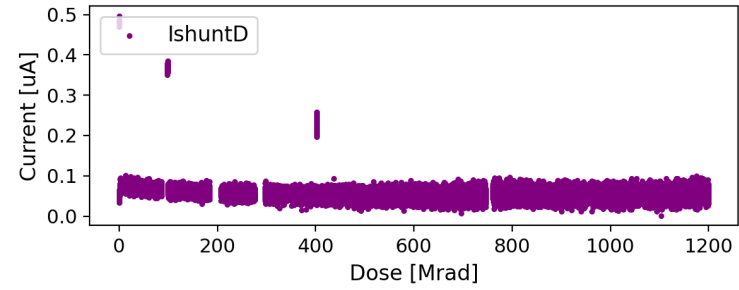
## Digital input current



## Analog shunt current



## Digital shunt current





# Conclusions

- Mostly done with analysing data from LBL X-ray irradiation and data looks mostly as expected
- Large increase in analog current is surprising
- Plan to do follow-up irradiation with chip in SLDO mode
  
- Also ramping up efforts on SLIPPER V2

**Thank you!**

**Any questions?**

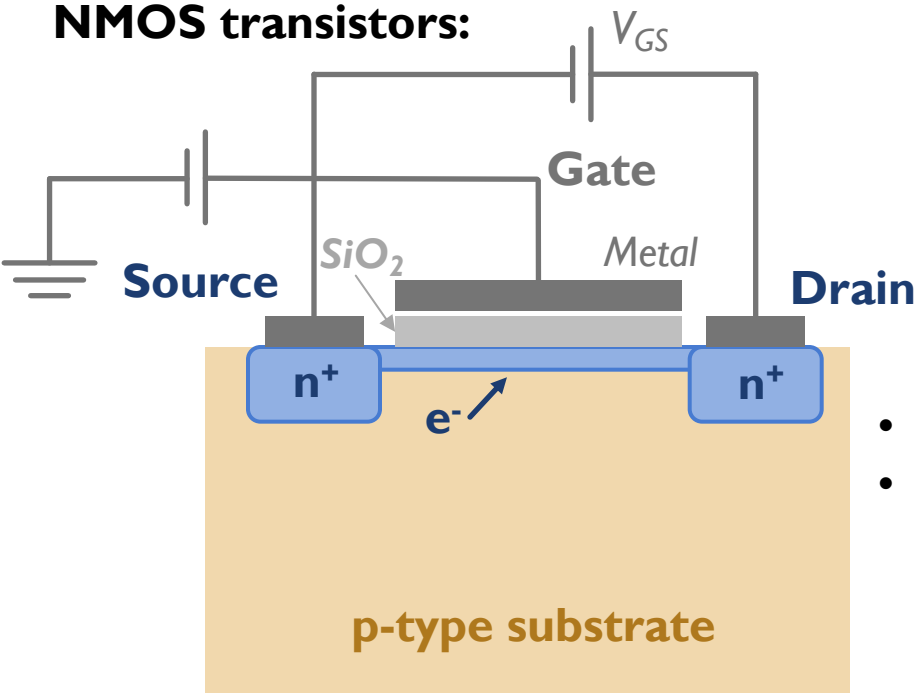
Table 6.5: Increase of the currents and voltages of the ITkPixV1 chip after irradiation to 1 Grad with X-rays at a dose rate of 4 Mrad/h.

Voltage/Current	Increase
<b>Currents</b>	
Main reference current $I_{ref}$	+ 4 %
Analogue input current $I_{in}$ analog	+ 14 %
Digital input current $I_{in}$ digital	+ 9 %
Analogue shunt current $I_{shunt}$ analog	+ 5 %
Digital shunt current $I_{shunt}$ digital	+ 5 %
<b>Voltages</b>	
Analogue input voltage $V_{inA}$	+ 3 %
Digital input voltage $V_{inD}$	+ 3 %
Analogue reference voltage $V_{refA}$	+ 12 %
Digital reference voltage $V_{refD}$	+ 8 %
Analogue LDO output voltage $V_{DDA}$	+ 14 %
Digital LDO output voltage $V_{DDD}$	+ 9 %
ADC reference voltage $V_{refADC}$	+ 8 %
SLDO offset voltage $V_{offset}$	+ 1 %

# Transistors

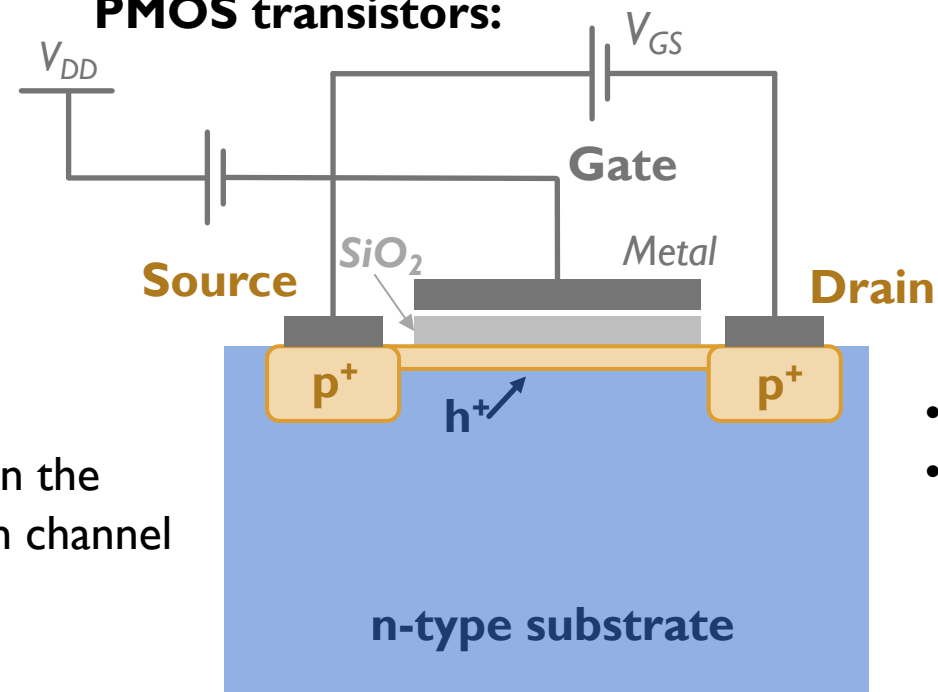
- MOSFET transistors are the building of current (pixel detector) electronics
- Working principle:
  1. Voltage is applied to gate to induce a channel of free charge carriers below the Si-SiO<sub>2</sub> surface
  2. Voltage applied between source and drain allow charge carriers to move → current

**NMOS transistors:**



- $V_{GS} > 0$
- Electrons in the conduction channel

**PMOS transistors:**



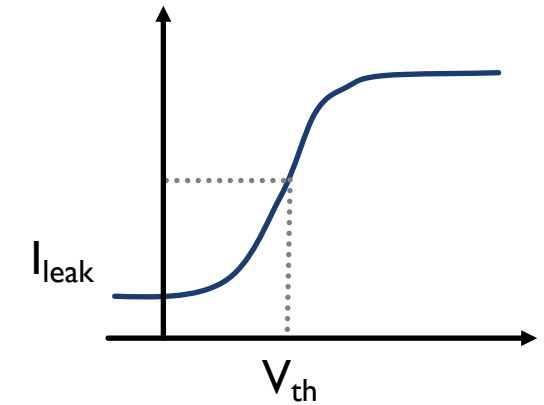
- $V_{GS} < 0$
- Holes in the conduction channel



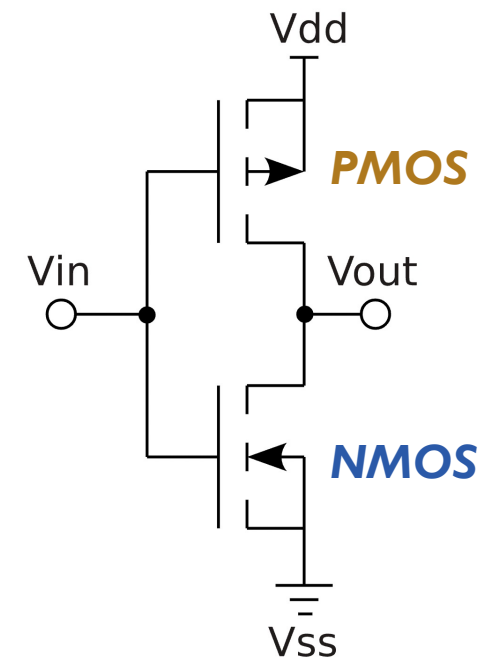
# Transistors part II

- Important characteristics of transistors include:
  - Transistor leakage current ( $I_{leak}$ ) → current when no voltage  $V_{GS}$  is applied
  - Threshold voltage ( $V_{th}$ ) → voltage at which the transistor turns on
- Various logic gates can be constructed from combinations of PMOS and NMOS gates
- E.g. Inverter gate → if you input 0, you get 1 and vice versa

Transistor turn-on curve



CMOS Inverter

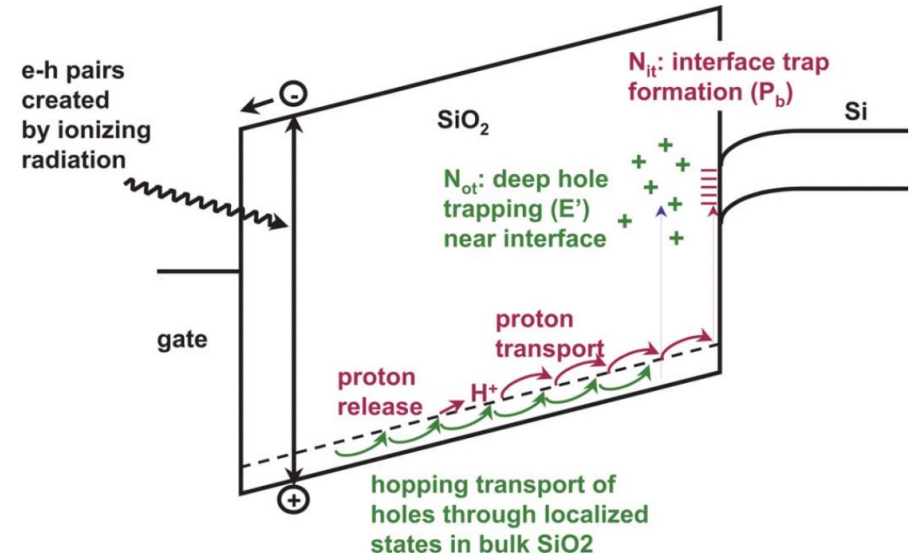


# Damage to SiO<sub>2</sub>

- In readout electronics, the damage to the SiO<sub>2</sub> and at the Si-SiO<sub>2</sub> interface are more important
- Mainly caused by ionization creating charged defect state in the oxide or at the interface → high electric fields exist in oxides, which separate the charge carriers

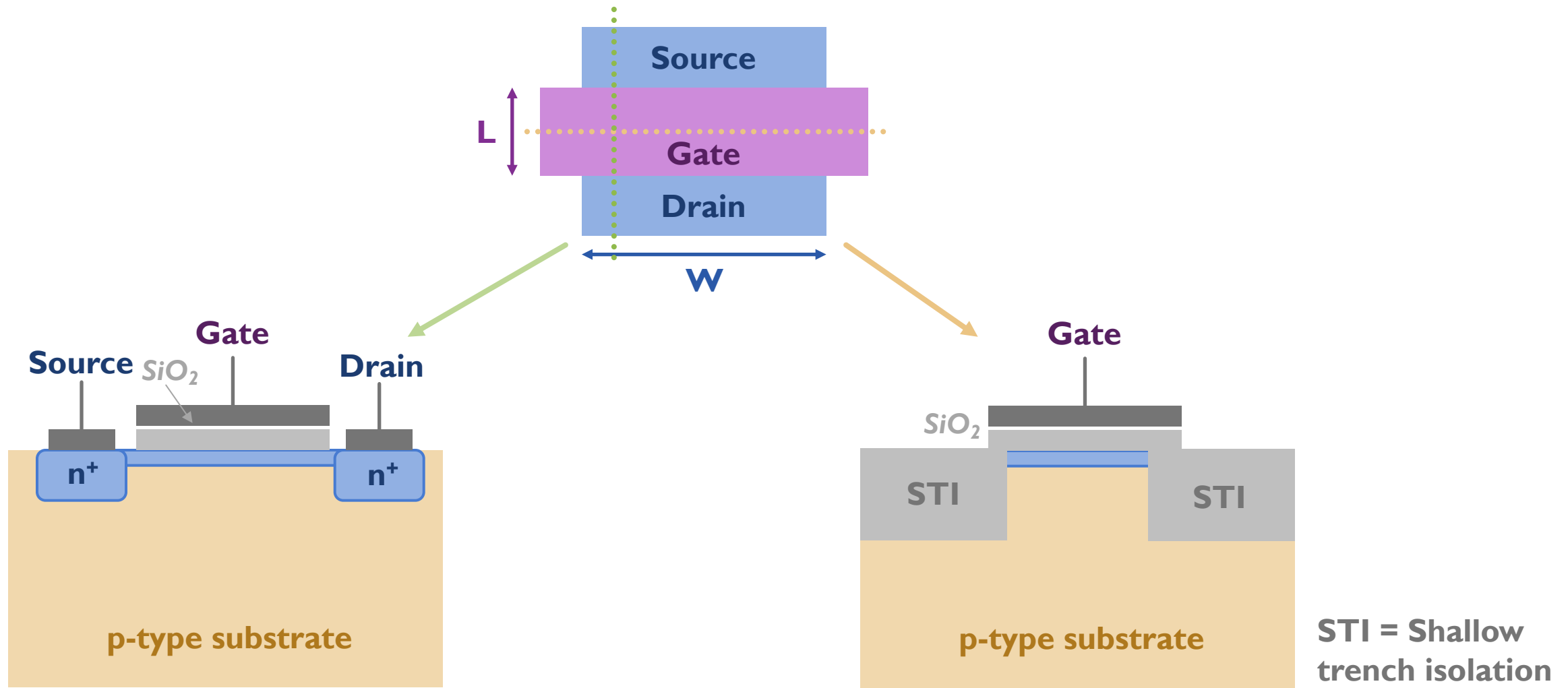
Two different effects to consider:

- Oxide charges (SiO<sub>2</sub>) → defects in SiO<sub>2</sub> are always donor-like (positive), occurs relatively quickly
- Interface states (Si-SiO<sub>2</sub> surface)
  - Impurity hydrogen ions released from lattice
  - Give rise to new interface states which serve as traps
  - Slower process due to lower mobility of hydrogen ions
  - Can be both acceptor and donor like, depending on material
  - Interface traps are **negatively charged in NMOS** (under positive bias) and **positively charged in PMOS** (under negative bias)



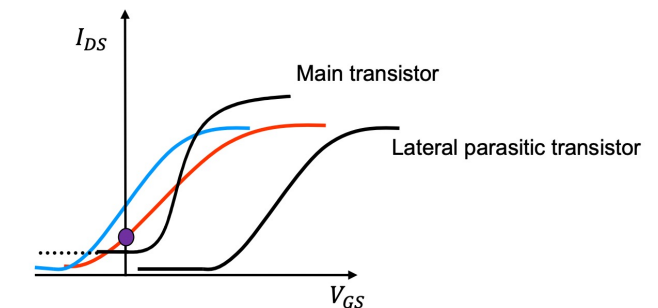
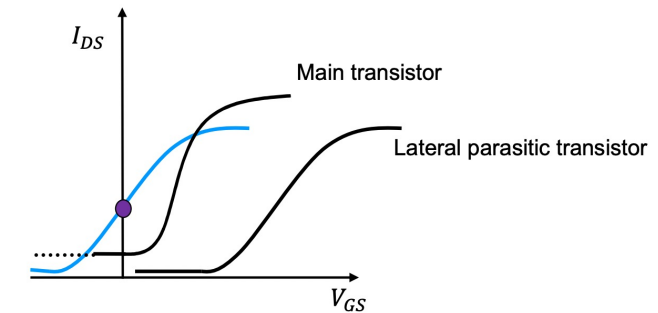
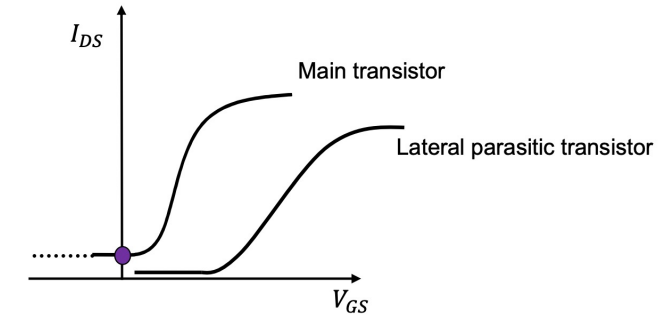
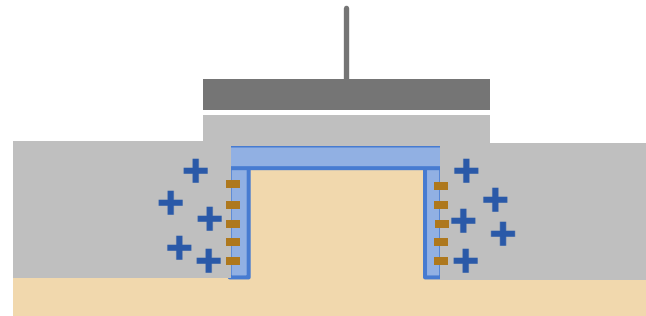
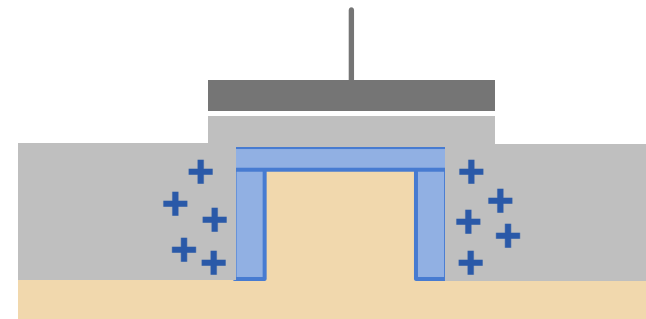
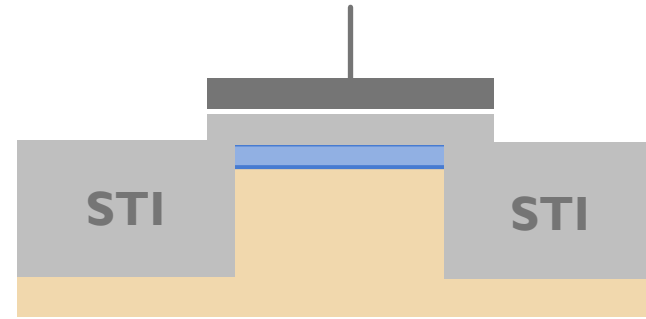
	NMOS	PMOS
Oxide charges	+	+
Interface traps	-	+

# Transistors



# Edge effects - NMOS

- Depending on transistor type, TID damage effects can look different
- Consider effects of radiation damage in STI
- In NMOS transistors:
  1. Fast build-up of positive oxide charges
    - opens up another channel through which electrons can flow between source and drain
    - Leakage current increases
    - Threshold voltage decreases
  2. Slower build-up of negative interface charges
    - Counteracts the effect of positive oxide charges
    - Leakage current decreases
    - Threshold voltage increases





# Edge effects - PMOS

- In PMOS transistors:
    1. Fast build-up of positive oxide charges
      - Holes in the conduction channel, so no additional channel opens up
      - Leakage current does not increase
      - Threshold voltage decreases
    2. Slower build-up of positive interface charges
      - Same effect as oxide charges
      - Threshold voltage increases further
- Mechanism known as Radiation Induced Narrow Channel Effect (RINCE)

